



009017-000015.KAG.206211/am

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re U. S. application of:
William M. Ayers

Serial No. ~~40/186,150~~

Filing Date: August 6, 2001

METHOD AND APPARATUS FOR THE
PREPARATION OF HIGH PURITY
PHOSPHINE OR OTHER GAS

) Before the Examiner:
) Group Art Unit: 1741

I hereby certify that this correspondence is
being deposited with the United States Postal
Service as first class mail in an envelope
addressed to the Assistant Commissioner for
Patents, Washington, D.C. 20231 on:

February 12, 2003

(Date of Deposit)

Kenneth A. Gandy

Name of Registered Representative

Signature

February 12, 2003

Date of Signature

27
11/B
W.M.
10/24/03

RESPONSE TO RESTRICTION REQUIREMENT

10/24/2003 WMITCHEL 00000000 233030 0172000

Assistant Commissioner for Patents
Washington, DC 20231

01 FC:1201
02 FC:1202

84.00 DA
54.00 DA
Sir:

This is in response to the Office Action dated November 12, 2002. Please
provide any extensions of time that may be necessary and charge any fees that may
be due, to Deposit Account No. 23-3030, but not to include the payment of any issue
fees.

IN THE CLAIMS:

Please add the following new claims.

--32. (New) A chemical reactor system for generation of high purity gas for
semiconductor fabrication, comprised of:
a source of microwave radiation;
a reaction chamber for receiving a precursor material for generating said gas,
said reaction chamber adapted to generate said gas under pressure;

B1

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TC 1700